

QUERY CONTROL FORM		RTIS USE ONLY	
Application No. <u>10/689,332</u>	Prepared by <u>Lois Stone</u>	Tracking Number <u>6015838</u>	
Examiner-GAU <u>Sikder - 2872</u>	Date <u>10/22/04</u>	Week Date <u>9/27/04</u>	
	No. of queries <u>1</u>	IFW	

JACKET

a. Serial No.	f. Foreign Priority	k. Print Claim(s)	<u>p. PTO-1449</u>
b. Applicant(s)	g. Disclaimer	l. Print Fig.	q. PTOL-85b
c. Continuing Data	h. Microfiche Appendix	m. Searched Column	r. Abstract
d. PCT	i. Title	n. PTO-270/328	s. Sheets/Figs
e. Domestic Priority	j. Claims Allowed	o. PTO-892	t. Other

SPECIFICATION

- a. Page Missing
- b. Text Continuity
- c. Holes through Data
- d. Other Missing Text
- e. Illegible Text
- f. Duplicate Text
- g. Brief Description
- h. Sequence Listing
- i. Appendix
- j. Amendments
- k. Other

CLAIMS

- a. Claim(s) Missing
- b. Improper Dependency
- c. Duplicate Numbers
- d. Incorrect Numbering
- e. Index Disagrees
- f. Punctuation
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MESSAGE

Please provide a copy of the PTO-1449 form with the citations either initialed or lined through. Copy provided for reference.

Thank you,

initials LS

RESPONSE

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INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>	Docket Number (Optional) TWI-12730	Application Number NEW
	Applicant(s) Minna Hovinen et al.	
	Filing Date HEREWITH	Group Art Unit Unknown

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	*AA	4,522,510	06/11/1985	Rosencwaig et al.	374	7	04/01/1983
	*AB	4,636,088	01/13/1987	Rosencwaig et al.	374	5	05/21/1984
	*AC	4,710,030	12/01/1987	Tauc et al.	356	432	05/17/1985
	*AD	4,854,710	08/08/1989	Opsal et al.	356	432	07/23/1987
	*AE	4,999,014	03/12/1991	Gold et al.	356	382	05/04/1989
	*AF	5,074,669	12/24/1991	Opsal	356	445	12/12/1989
	*AG	5,181,080	01/19/1993	Fanton et al.	356	381	12/23/1991
	*AH	5,298,970	03/29/1994	Takamatsu et al.	356	349	10/01/1992
	*AI	5,973,787	10/26/1999	Aspnes et al.	356	369	05/12/1998
	*AJ	5,978,074	11/02/1999	Opsal et al.	356	72	07/03/1997
	*AK	6,052,188	04/18/2000	Fluckiger et al.	356	369	07/08/1998
	*AL	6,081,330	06/27/2000	Nelson et al.	356	318	09/18/1998
	*AM	6,268,916	07/31/2001	Lee et al.	356	369	05/11/1999
	*AN	6,512,815	01/28/2003	Opsal et al.	378	89	05/06/2002
	*AO	6,535,285	03/18/2003	Opsal et al.	356	369	02/08/2000

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	*AP	WO 99/02970	01/21/1999	PCT	G01N	21/21		
	*AQ	WO 00/68656	11/16/2000	PCT	G01J	4/00		

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

	*AR	L. Zhou et al., "Use of a New Thermal Wave Technology for Ultra-Shallow Junction Implant Monitoring," <i>Proceedings of the X International Conference on Ion Implantation Technology</i> , June 1998, Kyoto (Japan), pp. 1-4.
	*AS	A. Salnick et al., "Quantitative Photothermal Characterization of Ion-Implanted Layers in Si," <i>25th Review of Progress in QNDE</i> , Snowbird (Utah), July 19-24, 1998, pp. 1-15.
	*AT	U.S. Patent Application No. 09/499,974, filed February 8, 2000, entitled "Combination Thermal Wave and Optical Spectroscopy Measurement System," (5 drawing pages included) by Jon Opsal et al., 29 pages in length.

Examiner	Date Considered
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	